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Upgrade EMU CMS

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Muon Subsystem







CSC Upgrade LS1



•Original design unfinished – ME4/2 not built, because of finance restrictions, it was decided to postpone the construction of the ME4/2 region (72 CSCs) until the first LHC shutdown

- •72 ME4/2 chambers to complete system
 - Identical to chambers already built and working well
 - Increase redundancy of system
 - •Efficient triggering at high luminosities



Why ME4/2 upgrade?



With ME4/2, we can change the trigger Condition to be 3/4 Coincidence instead of 2/3 • Decrease in fake rate

(predicted)

Prediction of adding ME4/2 from simulation





Status Muon Subsystem

 $\begin{array}{c} ME1/1 \ 72 \ 1.5 \times 0.5 \ m^2 \\ ME1/2 \ 72 \ 1.6 \times 0.8 \ m^2 \\ ME1/3 \ 72 \ 1.7 \times 0.9 \ m^2 \\ ME2/1 \ 36 \ 1.9 \times 1.25 \ m^2 \\ ME3/1 \ 36 \ 1.7 \times 1.25 \ m^2 \\ ME4/1 \ 36 \ 1.5 \times 1.25 \ m^2 \\ ME2/2 \ 72 \ 3.2 \times 1.3 \ m^2 \\ ME3/2 \ 72 \ 3.2 \times 1.3 \ m^2 \\ ME4/2 \ 72 \ 3.2 \times 1.3 \ m^2 \\ 540 \ CSCs \ (cover \ about \ 6000 \ m^2 \) \\ 2.5 \ 10^{**}6 \ anode \ wires \\ 210816 \ anode \ readout \ channels \\ 273024 \ cathode \ readout \ channels \\ \end{array}$





CSC Production





CSC Production



Width (top), 1530 mm Width (bottom), 895 mm Length, mm 3380 mm Wire per plane 1028 Wire ch. per plane 64 Strip ch. per plane 64 HV segments per plane 5 Chamber weight, kg 276



Run1/2 CSC







CMS Luminosity

CMS Integrated Luminosity, pp, 2015, $\sqrt{s}=$ 13 TeV





UF/ PNPI HV system



| 1 | Voltage regulation | 0 – V max = 4000 V |
|---|--------------------------------|--------------------|
| 2 | Voltage regulation step | 20 V |
| 3 | Voltage measurement resolution | 10 V |
| 4 | Max current per channel | 100 mkA |
| 5 | Current measurement resolution | 100 nA |

Muon Overlap Track Finder



Overlap region: $0.8 < /\eta / < 1.25$ The data of the three systems are implemented for the trigger decision: CSC, DT, RPC.





LHC Luminosity







GIF++ operational since April. The 13.9 TBq137Cs source is ~19 times stronger than the old GIF one (0.76 TBq). Attenuation filters allow a wide variation of the γ -flux. A muon beam is available.H4. 24.12.2015











24.12.2015











Gas studies



New regulations on greenhouse gas emission could hit us as soon as 2025 (40% reduction) and 2050 (100%).

A number of possible candidates for replacing CF4were proposed

Collaborators at PNPI have began investigating properties of such gases when used in Ar+CO₂ based gas mixtures

| Molecular name | Chemical formula | CAS | Refrigerant identifier | GWP | Life time in athmosphere, years |
|-----------------------|---------------------------------|-----------|---------------------------|-------|------------------------------------|
| Carbon Dioxide | CO ₂ | 124-38-9 | R744 | 1 | 50-200 |
| Tetrafluoromethane | CF_4 | 75-73-0 | R14 | 7390 | 50000 |
| Trifluoroiodomethane | CF₃I | 2314-97-8 | R13I | 0 | <1 |
| Hexafluoroethane | C_2F_6 | 76-16-4 | R116 | 12200 | 10000 |
| Octafluoropropane | C_3F_8 | 76-19-7 | R218 | 8830 | 7000 |
| Octafluorocyclobutane | c-C ₄ F ₈ | 115-25-3 | RC318 | 10300 | 3000 |

All these gases are used for dry plasma etching primarily related to silicon technology in microelectronics .•

CF3I has comparable Si-etching properties as CF4. So it is a good candidate



Straw aging test set up



Both aging tests and gas mixtures study are available

Attachment for electrons E ~ 0.01–0.5 eV in CF3I is 200 high in compare with CF4



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ME4/2 Upgrade

